

SPECIFICATION

Paragraph beginning at page 5, line 4:

A₁ FIG. 1 shows a schematic top view of a wafer management system in accordance with an embodiment of the present invention. In accordance with FIG. 1 there is provided a first stationary storage system 100 which is capable of storing a plurality of wafers, for example, 1000, 5000, or 10000 wafers. The first stationary wafer storage system 100 comprises a first buffer 110, which will be discussed in detail in connection with FIG. 2. To avoid a cross contamination of the wafers stored in the first buffer 110, the wafers are stored in a laminar gas flow within said buffer 110. The first stationary wafer storage system 100 further comprises a first load-and-unload station 115. This first load-and-unload station 115 is provided with first reading means 140 for reading the information provided on the wafers and/or on said first intra-bay pods 130. This first reading means 140 may be realized, for example, by a barcode reading system and/or through any suitable optical character recognition (OCR) system. The first load-and-unload station 115 is further provided with first writing means 150 for writing information provided on the wafers and/or on said first intra-bay pods 130, ~~for example, by the first writing means 140.~~ The first writing means 150 may be realized, for example, through a barcode write system. The first stationary wafer storage system 100 further comprises a second load-and-unload station 184 which may also comprise labeling and reading means.

Paragraph at page 6, line 22:

A₂ The term "full" is a convenient abbreviation that qualifies a pod that carries at least one wafer, but ~~that not necessarily carries wafers~~ in all available wafer slots. The term "empty" is a convenient abbreviation that qualifies a pod that is able to receive at least one wafer, but does not necessarily ~~does not~~ carry any wafer.